

## **COLLECTION ASSEMBLY AND SEMICONDUCTOR PRE-CLEANING CHAMBER**

### **ABSTRACT**

The invention provides a collection assembly and a semiconductor pre-cleaning chamber, which relate to the semiconductor processing apparatus field. The collection assembly is configured to collect particle impurities in the semiconductor pre-cleaning chamber, and includes a protection plate and a collection plate arranged at an interval in the semiconductor pre-cleaning chamber. The protection plate is annular. A plurality of first through-holes are arranged at the protection plate and configured for the process gas in the semiconductor pre-cleaning chamber to pass through. The collection plate is located on a side of an air outlet end of the first through-holes and configured to capture at least a part of the particle impurities in the semiconductor pre-cleaning chamber passing through the first through-holes. With the collection assembly of the present disclosure, the particle impurities can be effectively collected, the residual of the particle impurities is relatively few, which is not easy to contaminate an inner wall of the semiconductor pre-cleaning chamber. The risk of the wafer being contaminated again after pre-cleaning is also relatively low.

Fig. 1